

Doping Furnace (Ultra Clean Samples)

- Forming phosphorus diffusion
- Gas phase diffusion
- Samples : Pieces 4" wafer
- Phosphorous Doping
 - POCL₃ source
- Carrier gas: N₂
- Drive-In Anneal
- Temperature: 780°C to 1050°C
- Trans-LC cleaning for tubes
 - Industry standard
 - Highly effective cleaning



